

Nordson T&I Portfolio for Semiconductor Applications - Front, Mid and Back-End





Our Global Footprint



Our Values & Philosophy

Integrity

We are honest with employees, customers, shareholders, the media, and ourselves. We will do what is right. We will not compromise standards.

Respect For People

We value employees.
We thrive on teamwork,
collaboration and diversity.
We will not compromise
safety. We communicate
openly and honestly.
We give back to our
communities.



Customer Passion

Quality and service come first.

We expect more from ourselves than our customers do.



Excellence

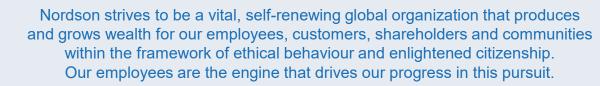
We expect the best from management, co-workers and ourselves. We are not satisfied with work that is "average" or "OK." We seek innovative approaches to create value.



Energy

We approach challenges
with an attitude of "lean
forward, let's get it done."
Enthusiasm drives the pace
of our work.
We care...complacency
is worse than our
toughest competitor.









Diversified Board of Directors

56% diverse board (3 gender and 2 racially or ethnically diverse)

8 out of 9 independent directors

7 years average tenure



Strong Culture and Values

Nordson Impact Invests 5% of domestic pre-tax earnings in communities

Paid time off for volunteer hours

Employee support programmes, including Matching Gifts



Environmental Stewardship

Product design improvements focused on reducing customers' material utilization

Journey to Zero adverse impacts to employees and community



Commitment to ESG

Environmental, Social, and Governance

With a global baseline established, we are pleased to take the next step in our ESG journey by establishing the following climate action targets:



Achieve a 50% reduction in net Scope 1 and Scope 2 CO2 emissions by 2030*



Achieve net zero Scope 1 and Scope 2 CO2 emissions by 2050



Procure 70% of electricity from renewable sources by 2050





Nordson T&I Portfolio for Semiconductor Applications - Front, Mid and Back-End



Competitive Advantages

Technology Leadership

- Differentiated technology; Best-in-Class Test, Inspection & Metrology systems and sensors
- Proprietary technology ~250 active or pending patents in the portfolio
- Algorithm expertise
- Widest portfolio of superior solutions across the SMT and Semiconductor segments
- Market creator; Technology pioneers
- Innovator: Continued investment in technology roadmaps



Operational Excellence

- Global footprint
- Global manufacturing
- o Strategic business discipline
- Commitment to Environment,
 Social and Governance (ESG) pillars
 - Commitment to reducing carbon footprint
 - Corporate social responsibility, corporate donations & employee wellness
 - Solid governance policies and procedures

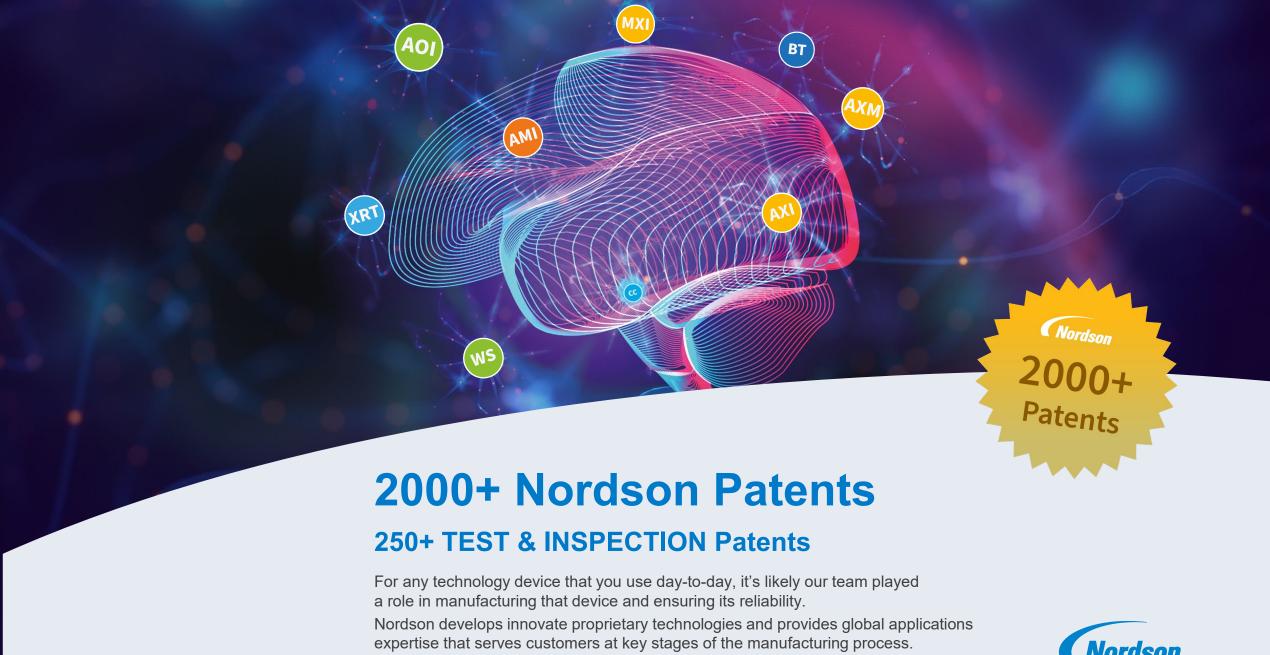


Customer Intimacy / Centricity

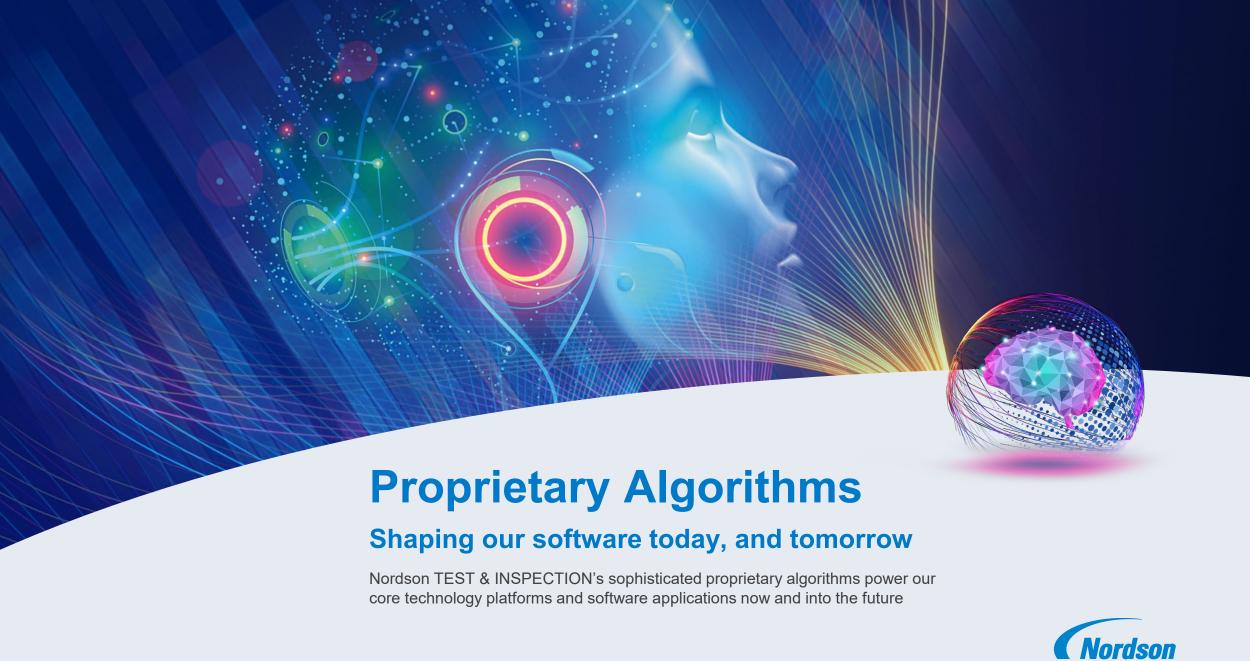
- Market creator solving customer challenges
- Meaningful customer relationships focused on meeting/exceeding customer needs into the future
- In-depth application expertise
- o Dedicated customer support







TEST & INSPECTION



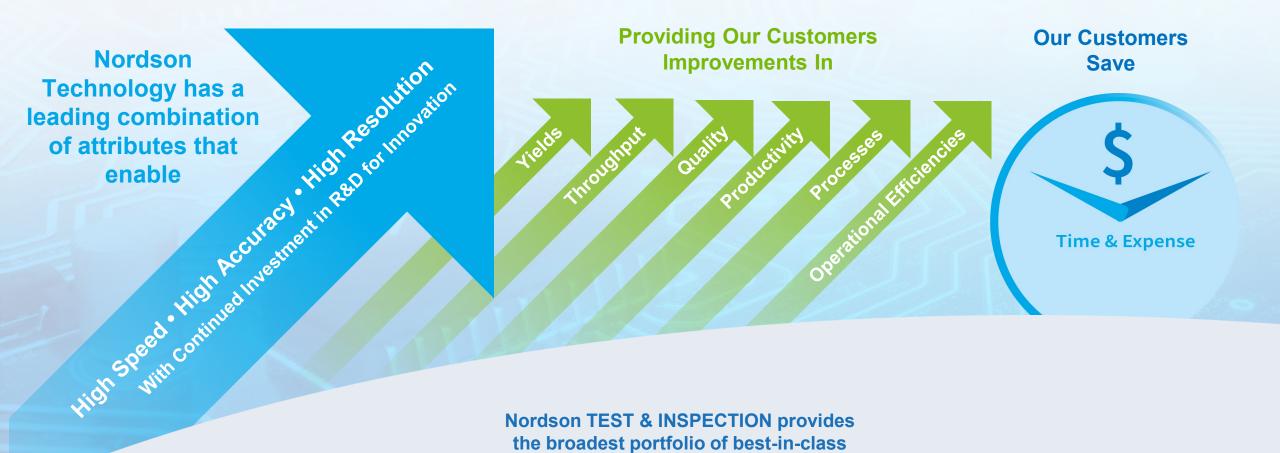


Driving cutting-edge Inspection & Metrology solutions

Nordson TEST & INSPECTION's industry-leading, advanced application software and global applications expertise serves customers at key stages of the manufacturing process. Incorporating sophisticated, proprietary algorithms and integrating the latest Machine Learning (ML), Artificial Intelligence (AI) and Deep Learning (DL) capabilities.



Competitive Advantages Across Portfolio



Nordson TEST & INSPECTION provides the broadest portfolio of best-in-class Inspection and Metrology Solutions for Semiconductor and SMT high-end applications



Core Technologies Across T&I

AOI

Multi-Reflection Suppression[®] (MRS[®]) Sensor Technology





QuadraNT™
X-ray Tube
& AspireFP™
Detector





C-SAM[®] & SpinSAM[™] Acoustic Microscope





Multi-Functional
Cartridge
(MFC)





WaferSense® Metrology Sensors



Advanced, industry-leading, proprietary technology across applications.



Multi-Reflection Suppression® (MRS®) Sensor Technology

Metrology-Grade Accuracy at Production Speed



MRS sensor captures multiple points of 3D imagery simultaneously and in parallel. Sophisticated fusing algorithms merge the images together

Sophisticated Algorithms Eliminate Reflection-Based Distortions





MRS technology identifies and rejects multiple reflections from shiny and specular surfaces for highly accurate inspection and measurement. Provides an ultra-high resolution, full colour, 3D representation







QuadraNT™ X-ray Tube, Onyx™ Detector

QuadraNT X-ray Tube



QuadraNT tubes use proprietary "filament free" technology for continuous service Dual Mode X-ray Tube



Flexible & intelligent dual mode X-ray tube. Switch between modes revealing the tiniest details Onyx Detector



HL 6.5 Mpix, superior performance, lower noise, faster imaging with highest clarity and brilliance High-Speed High-Resolution



Onyx consists of a high-speed, low-noise, radiation-tolerant, CMOS image sensor



XRT CORE TECHNOLOGIES



C-SAM® & SpinSAMTM Acoustic Microscope

Maximum Image Clarity & Quality Data



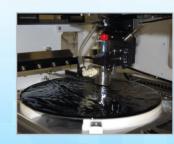
Transducers are carefully developed and manufactured to deliver maximum image clarity and quality data by our transducer lab located near Chicago, Illinois

Transducers Optimized for Applications



Broad range of standard transducers. We also have the expertise to optimize the design parameters for specific applications

Waterfall Nonimmersion Scanning



Non-immersion scanning minimizes the risk of contamination and false bond indications



(AMI) CORE TECHNOLOGIES



Multi-Functional Cartridge (MFC)

Industry Unique Cartridge



Designed for use with automatic test routines enabling multi-surface test patterns for complex hybrid packages

Switch Applications In Seconds



Ultra-quick application changeover

Multiple Tools All In One Cartridge



Switch applications effortlessly: wire pull, bump shear & tweezer pull



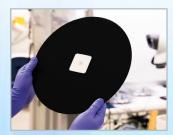
CORETECHNOLOGIES





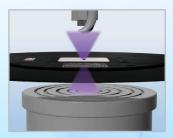
WaferSense® Metrology Sensors

Real-Time Sensor



On-board image processor "Sees" inside semiconductor equipment to capture three dimensional offset data (x, y and z) to quickly teach wafer transfer positions with accuracy to 50µm

Repeatable, Reproducible **Semiconductor Setups**



Downward view Inspects more complex alignment mark shapes, upward view measures and inspects the components above, ATS also can simultaneously inspect

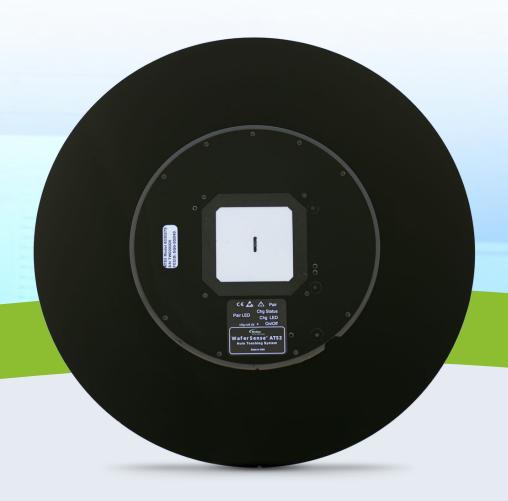
CyberSpectrum™ Software



Speed up Troubleshooting, & Lower Consumable Expense CyberSpectrum™ provides numerical and visual feedback for real-time measurement and analysis

WS CORE TECHNOLOGIES



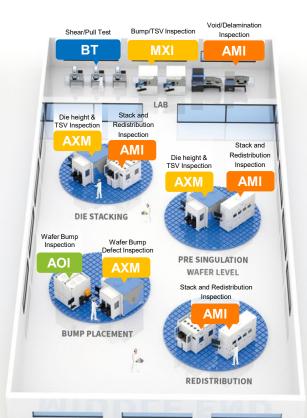




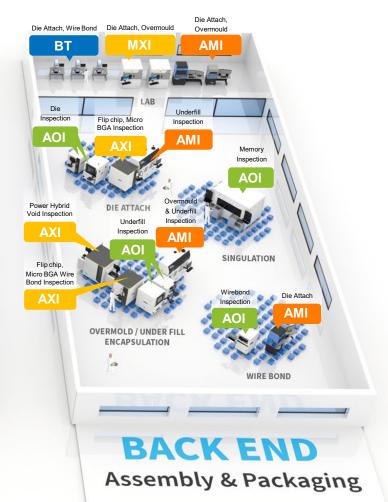
Nordson TEST & INSPECTION's Best-in-Class Test, Inspection and Metrology Solutions











Providing the Ultimate Combination of High Resolution, High Accuracy and High Speed to Improve Yields, Processes and Productivity

Semiconductor Front End

WaferSense® Semiconductor Front-End Measurement Sensors



Auto Multi Sensors

Speed measuring levelling, vibration and humidity with a thinner, lighter, all-in-one multi sensor

Monitor humidity when wafers are in the FOUP

*AHS also available for RH



Auto Vibration and Levelling Sensor

Speed simultaneous vibration and levelling measurements

Speed equipment qualification and shorten equipment maintenance cycles



Airborne Particle Sensors

Quickly identify, monitor and troubleshoot airborne particles down to .14 micron

Easily identify when and where the particles originate and measure the effectiveness of cleaning adjustments in real time

IPS - 24/7 detection of small particles in gas and vacuum lines



Auto Gapping System

Speed non-contact gap measurements and parallelism adjustments under vacuum for semi processes such as thin film, deposition, sputtering and etch

Improve uniformity, tool availability and repeatability



Auto Resistance Sensor

Shorten equipment maintenance cycles with 4-wire resistance sensor

Predict when a tool needs maintenance with quantitative analysis of measured mean resistance over time

Improve cell-to-cell process uniformity with objective and repeatable resistance measurements



Auto Teaching System

"See" inside equipment to capture dimensional offset data (x, y and z) to quickly teach wafer transfer positions

Lower particulate contamination with accurate wafer hand-off calibration, proper alignment and set-ups

World's Most Efficient & Effective Wireless Measurement Sensors



Semi Solutions for Front-End Tools

Semi	Sensor	Front-End Tools							
		Leveling	Vibration	Airborne Particles/ In-Line Particles	Gapping	Teaching	Relative Humidity (RH)	Resistanc e	
Front-End Semiconductor Tools	APS3 / APSRQ / IPS								
	ALS /AVLS	•	•						
	ATS / ATSR								
	AGS				•				
	AMS (L, V, RH)	•	•				•		
	ARS							•	Back-end packaging such as pillar bumping, RDLs, TSVs, and hybrid bonding
	AVS / AVLS	•	•						



Semi Solutions for Front-End Tools

AMS' **Applications**

Applications

- Epitaxy
- · Thermal oxidation/metallization
- Plasma vapor deposition; PVD
- · Chemical vapor deposition; CVD, ALD
- CMP
- Atomic layer deposition; ALD
- Photo lithography

NEW! V2

- Wet (chemical) etch, plasma etch
- Dry etch

- · Ion implant
- · Diffusion/furnace
- · Rapid thermal anneal; RTA, RTP
- Test and inspection
- Metrology
- · Micro contamination
- · Auto handling system; AMHS
- Module repair

APS3



Applications

- · Factory interface FI/EFEM Photo Lithography
- Diffusion/Furnace
- Test and Inspection
- Rapid Thermal Anneal; RTA, RTP
- Metrology
- Microcontamination
- · Auto Handling System; AMHS and Stockers

ATS2*

Applications

· Plasma vapor deposition; PVD

· Atomic layer deposition; ALD

· Wet (chemical) etch, plasma etch

· Chemical vapor deposition; CVD, ALD

· Chemical vapor deposition; CVD, ALD

- · Photo lithography
- · Wet (chemical) etch, plasma etch
- Dry etch
- · Ion implant
- Automated handling system

ARS



· Electrochemical Deposition; ECD

*Available in reticle form factor



World's Most Efficient & Effective Wireless Measurement Devices

For Front-End Semiconductor Applications



Proven and Adopted

- Major Semi fabs WW have adopted CYBE wireless measurement devices
- Adopted as the Best Known Method (BKM)

Most Efficient & Effective

- Travels anywhere a wafer or reticle travels
- Calibrations can be done under closed chamber processes
- Provides accurate, reliable and repeatable real-time data that saves time and expense compared to legacy methods

Save Time & Expense

- Improves yields and tool uptime
- Increases throughput
- Reduces resource needs
- Speeds equipment set-up, maintenance processes, troubleshooting, qualification and release to production.
- Speeds tool optimization, stabilization and standardization.
- Streamlines fab processes
- Establishes repeatable and verifiable standards



Superior Metrology Sensors

WaferSense® Auto Gapping System™ (AGS)

Achieve the Ideal Equipment Set-up



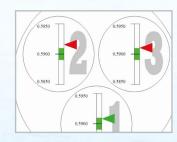
Speeds non-contact gap
measurements and
parallelism adjustments under
vacuum for semiconductor
processes such as thin-film
deposition, sputtering and
etch

3 Sensors Report Separate Readings



Non contact gap
measurement by sensing
capacitance from the top of
the AGS ensures inclination
and height are at the optimum
positions for a pedestal or
shower head

CyberSpectrum[™] Software



Quickly achieve exactly the gap you need, using the chamber readings at process pressure in numerical and graphical form



TOP PRODUCTS





Semiconductor Mid End

Widest Portfolio of Best-In-Class Test, Inspection & Metrology Solutions for Mid-End Semiconductor Wafer-Level and Advanced Packaging Applications



WX3000

Fast, 100% 3D/2D automated inspection and metrology

Powered by Multi-Reflection Suppression® (MRS®) technology

For features down to 25 micron at 25 WPH, 2-3X faster than competitive technology





XM8000

Unprecedented, automated in-line X-ray metrology and defect review

Powered by QuadraNT™ X-ray and AspireNT™ detector technology

For optically hidden features including voiding and fill levels, overlay, critical dimensions and more, with high throughput





Quadra Pro

Superior 3D/2D manual inspection

Powered by QuadraNT™ tube and Onyx® detector technology

For voiding inspection with submicrometer accuracy for features down to 100um. Higher resolution, faster frame rate and lower noise





SpinSAM

Fast, acoustic 100% inspection.

Powered by SpinSAM™ transducer technology

For applications down to 75um with >95% detectability at 40WPH with 100um resolution





AW300

Fast, acoustic 100% inspection.

Powered by C-SAM® transducer technology

For applications down to 75um with >95% detectability at 5.8WPH with 100um resolution. Widest frequency range ever achieved in production environment





4800 Integra

Factory-integrated test solution with automated sheer and cold pull testing

Powered by Core Cartridge Technology

For automated bond testing with maximum throughput in an operator free environment

Ultimate Combination of High Speed, High Accuracy and High Resolution



Semi Solutions for Mid-End

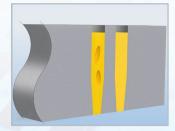
Semi	System			Mid-End		Technology	
				WL & AP			
		Wafer Bump	Copper Pillars	Solder Paste	Die Stacking	TSV	
	WX3000	•		•			AOI
_	XM8000						AXM
Mid-End	Quadra W8					•	MXI
Mid-	SpinSAM						AMI
_	AW300						AMI
	4800 Integra	•	•				ВТ



Superior Automated X-ray Inspection

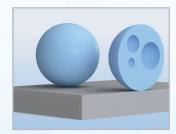
XM8000

TSV Metrology



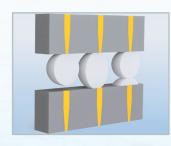
High throughput metrology of TSVs. Advanced 3D techniques are used to analyze shape, fill and voiding at sub-micron levels

Wafer Bump Metrology



Measure wafer bump characterization including voiding, presence, position, shape, size and bridging. Unlike optical tools, XM8000 can measure voids within the wafer bump

Wafer Level Packaging



The intelligent, self learning capability of XM8000 allows unrivalled detection of micro defects in complex packages

TOP PRODUCTS





Improves Yields Processes and Productivity



Superior Manual X-ray Inspection

QUADRA PRO

Onyx Detector



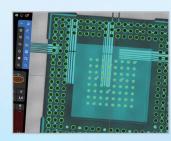
HL 6.5 Mpix superior performance, lower noise faster imaging with highest clarity and brilliance

Dual Mode X-ray Tube



Proprietary, high performance, flexible & intelligent dual mode X-ray tube. Switch between modes revealing the tiniest details

Revalution™ Software



Developed by our experts specifically for the proprietary high-end semiconductor application



MXI NEW PRODUCTS

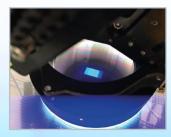




Superior WL&AP Automated Inspection System

WX3000TM

High Speed, Accuracy and Resolution



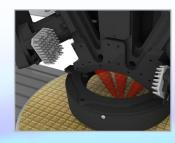
The ultimate combination of high speed, high resolution and high accuracy for waferlevel and advanced packaging applications to improve yields and productivity

Metrology-Grade Accuracy with MRS®



Sub-micrometer accuracy for features as small as 25 µm. Accurately inspect shiny or mirror-like surfaces. Attain repeatable and reproducible measurements

Fast, Inspection Performance



The MRS sensor that is 2-3x faster than alternate technologies, delivering greater than 25 wafers (300mm) per hour

(AOI) NEW PRODUCTS



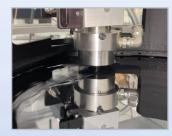
Improves Yields Processes and Productivity



Superior Acoustic Inspection

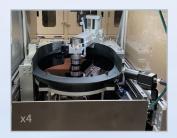
SpinSAMTM

Highly Efficient



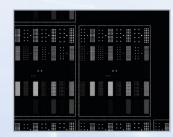
A continuous non-stop scan path provides the fastest data collection possible

40 Wafers Per Hour



4 combined scanners 40WPH each capable of 10WPH @ 100μm

Perfect Images



Single transducer image without any stitching artifacts



AMI NEW PRODUCTS

Improves Yields Processes and Productivity



Semiconductor Back End

Widest Portfolio of Best-In-Class Test, Inspection and Metrology **Solutions for Back-End Semiconductor Applications**



SQ3000

Superior, 100% inspection and metrology

Powered by Multi-Reflection Suppression® (MRS®) technology

World's first and only in-line system with CMM capability

For semi packaging, socket metrology, wire bond and die, solder balls and bumps. microsensors, IC, LGA, epoxy and underfill, substrate epoxy, photoresist on substrate

SQ3000+

Superior, 100% inspection and metrology

Powered by Multi-Reflection Suppression® (MRS®) technology

World's first and only in-line system with CMM capability with an even higher resolution

For semi packaging advanced /nextgeneration applications

MX3000

Fast. 100% simultaneous, dual-sided inspection

Powered by Multi-Reflection Suppression® (MRS®) technology

The only final vision inspection (FVI) system for memory modules after the I/O check

SQ3000M2

Superior inspection and metrology

Powered by Advanced Focus variation measurement sensor technology with proprietary high resolution optics

For Automated Optical Inspection of Advanced Micro Electronics including wirebonds

4000Plus

Superior bond testing and R&D prototype characterization

ВТ

Powered by Core Cartridge Technology

For wire and die adhesion and pull strength testing capable of a multitude of test types including micromaterials and standard bond tests for R&D or quality control



Quadra Pro

Superior 3D/2D manual inspection

Powered by QuadraNT™ tube and Onyx® detector technology

For voiding inspection with sub-micrometer accuracy for features down to 100um Higher resolution faster frame rate and lower noise

Superior automated X-ray inspection system

Powered by N24 X-Ray tube and CMOS DFP detector

For semiconductor chip, voiding for single/multi-panels or samples in trays

X#UHP

samples, wire bonds, flip

Superior automated X-ray inspection system

Powered by QuadraNT™ and Aspire™ technology

For component level inspection and highpower electronics modules up to fully assembled modules Focused platform with versatile fields of use

AMI

Superior, high-speed acoustic automated inline inspection

DF2400

Powered by Waterfall transducer and FACTS2

For simultaneous inspection of two travs or modules with precision of +/- 0.5um. Multiple scanning heads improves throughput ~2-7x previous tools

D9650

Superior lab-based acoustic microimaging

> Powered by C-SAM technology

Delivers unrivalled accuracy and robustness for failure analysis, process development material characterization and low volume production inspection

Gen7

Superior lab-based operator controlled and fully automated in-line acoustic inspection

Powered by C-SAM technology

For detecting delamination, voiding with the most sophisticated microscope for lab analysis and specialized high-resolution applications

Ultimate Combination of High Speed, High Accuracy and High Resolution



Semi Solutions for Back-End

Islands of Automation / In-Line

Com:	System		Back-End		Tashnalasy
Semi		CPU/GPU	Memory	Power Hybrid/IGBT	Technology
	Quadra Pro 5, 7	•	•	•	MXI
70	XS		•		AXI
Back-End	X#UHP			•	AXI
a c k	SQ3000M2	•	•	•	AOI
Δ	MX3000		•		AOI
	SQ3000	•	•	•	
	SQ3000+		•	•	AOI
	DF2400	•			AMI
	D9650	•		•	AMI
	Gen 7			•	AMI



Superior AOI, SPI, CMM System

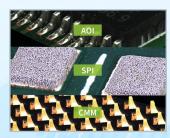
SQ3000+

Multi-Reflection Suppression® (MRS®)



The Ultimate Combination of High Speed, High Accuracy, and *Even Higher* Resolution

Multi-Function Capability



The SQ3000+ remains the only system on the market capable of performing AOI, SPI and CMM in-line

Award-Winning AOI Software



Ultra-fast programming, Auto Tune, AutoDefine, AutoTeach & advancing inspection algorithms to include deep learning capabilities



NEW PRODUCTS

Ideal for next-generation applications. The system is specifically designed for high-end applications including advanced packaging, BGA, mini-LED, advanced SMT, 008004/0201 SPI, socket metrology and other challenging CMM applications

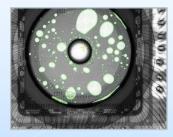
Improves Yields Processes and Productivity



Superior Automated X-ray Inspection

XS

High-resolution Automated X-ray Inspection



High-speed inspection of semiconductor samples, wire bonds and PCB-assembly boards for single/multi-panels or samples in trays

4 Advanced Technologies, One System



Transmission X-ray imaging (2D) with patented Slice-Filter- Technique™ (SFT), Off-Axis technology (2.5D) and 3D SART (Simultaneous Algebraic Reconstruction Technique)

Unique Advanced Algorithm Library



For electronic applications, component and solder-joint inspection on PCB, hybrid or chip level assembly, semiconductor and wire bond testing



TOP PRODUCTS

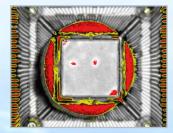




Superior Non-Destructive Inspection

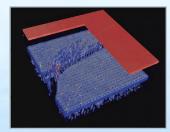
D9650

CSAM® (C-Mode Scanning **Acoustic Microscope)**



C-SAM® enhanced features accommodate the testing as well as performing standard C-SAM® operations

Industry Trusted Failure Analysis



Ideal for failure analysis, process development and low volume production environments

Powered by Our **Sonolytics 2 Software**



Maximize results and save time with the industry's leading easiest and intuitive interface software

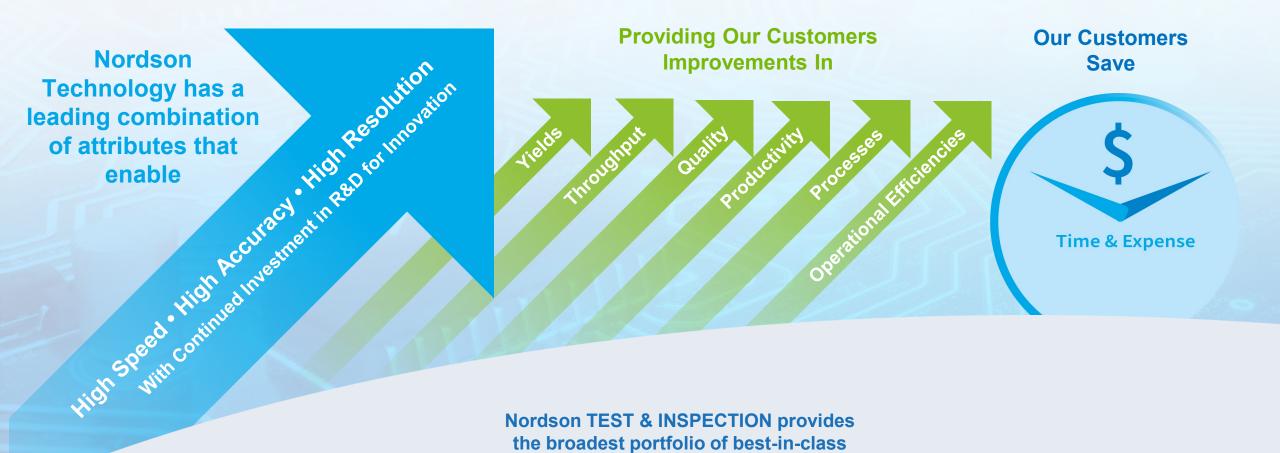




Improves Yields Processes and Productivity



Competitive Advantages Across Portfolio



Nordson TEST & INSPECTION provides the broadest portfolio of best-in-class Inspection and Metrology Solutions for Semiconductor and SMT high-end applications



Appendix



Semi Mid-End Systems

Widest Portfolio of Best-In-Class Test, Inspection and Metrology Solutions for Mid-End Semiconductor Wafer-Level and Advanced Packaging Applications

Ultimate Combination of High Speed, High Accuracy and High Resolution

WX3000™



- Fast, 100% 3D/2D automated inspection and metrology
- Powered by Multi-Reflection Suppresssion[®] (MRS[®]) technology
- For features down to 25 micron at 25 WPH, 2-3X faster than competitive technology

XM8000

X-Ray AXM



- Unprecedented, automated in-line X-ray metrology and defect review
- Powered by QuadraNT[™]
 X-Ray and AspireNT[™]
 detector technology
- For optically hidden features including voiding and fill levels, overlay, critical dimensions and more, with high throughput

QuadraW8

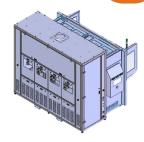
X-Ray MXI



- Superior autoload, manual, lab-based, X-Ray inspection
- Powered by QuadraNT™ X-Ray and AspireNT™ detector technology
- Industry-leading magnification and image quality revealing defects as small as 0.1um.

SpinSAM

Acoustic AMI



- Fast, acoustic 100% inspection
- Powered by SpinSAM™ transduser technology.
- For applications down to 75um with >95% detectability at 40WPH with 100um resolution.

AW300

Acoustic AMI



- Fast, acoustic 100% inspection
- Powered by C-SAM™ transduser technology.
- For applications down to 75um with >95% detectability at 5.8WPH with 100um resolution. Widest frequency range ever achieved in production environment.

4800 Integra®

Bond Test



- Factory-integrated test solution with automated sheer and cold pull testing
- Powered by Core Cartridge Technology
- For automated bond testing with maximum throughput and an operator free environment.



Semi Back-End Systems

Widest Portfolio of Best-In-Class Test, Inspection and Metrology Solutions for Back-End Semiconductor Applications

Ultimate Combination of High Speed, High Accuracy and High Resolution

AOI

SQ3000™+



 Superior, 100% inspection and metrology

SQ3000™

- Powered by Multi-Reflection Suppression[®] (MRS[®]) technology
- World's first and only inline system with CMM capability
- For semi packaging, socket metrology, wire bond and die, solder balls and bumps, microsensors, IC, LGA, epoxy and underfill, substrate epoxy, photoresist on substrate.

- Superior, 100% inspection and metrology
- Powered by Multi-Reflection Suppression[®] (MRS[®]) technology
- World's first and only inline system with CMM capability with an even higher resolution
- For semi advanced packaging, high-end SMT, mini and micro-LED, socket metrology, 0201 solder paste and other next-generation applications

SQ3000M2

AOI



- Superior, 100% inspection
- Powered by advanced megapixel technology
- Exceptional defect coverage with highresolution telecentric optics
- For wire bond, die placement and substrates

MX3000

AOI



- Fast, 100% simultaneous, dual-sided inspection
- Powered by Multi-Reflection Suppression[®] (MRS[®]) technology
- The only final vision inspection (FVI) system memory modules after the I/O check

4000 Plus



- Superior bond testing and R&D prototype characterization
- Powered by Core Cartridge Technology
- For wire and die adhesion and pull strength testing capable of a multitude of test types including micromaterials and standard bond tests for R&D or quality control



Semi Back-End Systems

Widest Portfolio of Best-In-Class Test, Inspection and Metrology Solutions for Back-End Semiconductor Applications

QuadraPro 5, 7 X-Ray MXI

- Superior 3D/2D manual inspection
- Powered by QuadraNT™ tube and Onyx® detector technology
- For voiding inspection with sub-micrometer accuracy for features down to 100um. Higher resolution, faster frame rate and lower noise.



- Superior automated X-ray inspection system
- Powered by N24 X-Ray tube and CMOS DFP detector
- For semiconductor samples, wire bonds, flip chip, voiding for single/multi-panels or samples in trays.



- Superior automated X-ray inspection system
- Powered by QuadraNT™ and Aspire™ technology
- For component level inspection and highpower electronics modules up to fully assembled modules Focused platform with versatile fields of use.

DF2400

Acoustic



- Superior, high-speed acoustic automated in-line inspection
- Powered by Waterfall transducer
- For simultaneous inspection of two trays or modules with precision of +/- 0.5um. Multiple scanning heads improves throughput ~2-7x previous tools.

D9650

Acoustic



- Superior lab-based acoustic microimaging inspection
- Powered by C-SAM technology
- Delivers unrivaled accuracy and robustness for failure analysis, process development, material characterization and low volume production inspection.

Gen7

Acoustic



- Superior lab-based, operator controlled and fully automated in-line acoustic inspection
- Powered by C-SAM technology
- For detecting delamination, voiding with the most sophisticated microscope for lab analysis and specialized highresolution applications.



